





PATENT Attorney Docket No. 07553.0044-00

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)
Hideki TANAKA	) Group Art Unit: 2878
Application No.: 10/644,745	) ) Examiner: J. Lee
Filed: August 21, 2003	) )
For: PLASMA LEAK MONITORING METHOD, PLASMA PROCESSING APPARATUS AND PLASMA PROCESSING METHOD	) Confirmation No.: 6213 ) ) )

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

## RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. §1.111

In response to the Office Action mailed September 20, 2006, the time period for response to which extends to December 20, 2006, Applicants respectfully request reconsideration of the above-identified application in view of the following remarks.

## **REMARKS**

## I. Status and Disposition of the Claims

Claims 1-12 are pending. No claims are amended herein.

Claims 1, 3-5, 7-9, 11 and 12 are allowed by the Examiner. Office Action at 2-3. Applicant thanks the Examiner for the indication of allowable subject matter. However, claims 2, 6 and 10 are rejected by the Examiner under 35 U.S.C. §102(e) as being